

WHAT IS CLAIMED IS:

1 - 40. (Previously Cancelled)

41-69. (Canceled)

70. (New) An exposure apparatus comprising:

an illumination optical system for illuminating a reticle with illuminating light from a light source;

a projection optical system for projecting a pattern, which has been formed on the reticle, onto a photosensitive substrate;

a holding unit for holding the reticle;

a reticle transport system for transporting the reticle;

a substrate stage capable of holding and moving the substrate; and

a substrate transport system for transporting the substrate,

wherein at least one of a pair of said reticle transport system and said holding unit and a pair of said substrate transport system and said substrate stage is accommodated in a partitioned circulation space in which inert gas is filled and the inert gas is circulated by a circulating system having a temperature control mechanism.

71. (New) The apparatus according to claim 70, further including an air conditioning system which circulates temperature controlled gas in a space other than the partitioned circulation space.

72. (New) The apparatus according to claim 70, wherein the partitioned circulation space includes a connecting member which has airtightness and flexibility.

73. (New) The apparatus according to claim 70, further comprising a position detection system for detecting an alignment mark on the substrate,

wherein a pattern projection region for projecting the pattern onto the substrate by said projection optical system is formed at a position that is off-centered toward the side of said position detection system from the projection center of said projection optical system.

74. (New) The apparatus according to claim 70, wherein said substrate transport system is disposed on the side of the projection region with respect to the projection center.

75. (New) The apparatus according to claim 74, wherein said apparatus has a plurality of said position detection systems, and said plurality of position detections systems are disposed on the side of said projection region with respect to the projection center.

76. (New) The apparatus according to claim 70, wherein a projection region of the pattern, which region is formed on the substrate via said projection optical system, is formed at a position that is off-centered with respect to the projection center of said projection optical system, and said mask transport system is disposed on the side of the illumination region with respect to the projection center.

77. (New) The apparatus according to claim 70, wherein a projection region of the pattern, which region is formed on the substrate via said projection optical system, and an illumination region on the mask, are formed at positions that are off-centered to the same side with respect to the projection center of said projection optical system, and said mask transport system and said substrate transport system are disposed on the side of the projection region and an illuminating region with respect to the projection center.